

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Satoru Okamoto                      Art Unit : 1792  
Serial No. : 10/689,617                      Examiner : Mahmoud Dahimene  
Filed : October 22, 2003                      Conf. No. : 4799  
Title : METHOD FOR CLEANING PLASMA ETCHING APPARATUS, METHOD  
FOR PLASMA ETCHING, AND METHOD FOR MANUFACTURING  
SEMICONDUCTOR DEVICE

**MAIL STOP AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450


NOTICE OF APPEAL

Applicant hereby appeals to the Board of Patent Appeals and Interferences from the action dated August 3, 2009, finally rejecting claims 1-95.

The amount of \$540 for the appeal fees are being paid concurrently herewith on the Electronic Filing System (EFS) by way of Deposit Account authorization. Please apply any other charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: 2 November 2009

  
\_\_\_\_\_  
Roberto J. Devoto  
Reg. No. 55,108

Fish & Richardson P.C.  
1425 K Street, N.W.  
11th Floor  
Washington, DC 20005-3500  
Telephone: (202) 783-5070  
Facsimile: (877) 769-7945